

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet

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of

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Complete if Known

Application Number	10/625,769
Filing Date	07/23/2003
First Named Inventor	Brian G. Hoover
Art Unit	3738
Examiner Name	CHATTOPADHYAY, U.
Attorney Docket Number	13621-43433

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
MDV	1	US- 5061057	10/29/1991	KUMAKURA, Minoru, et al.	
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FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ Number ⁴ Kind Code ⁵ (if known)				

Examiner
Signature

M. Vargst

Date

Considered

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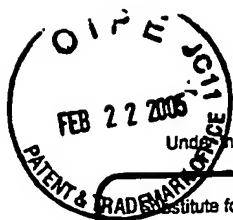
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Sheet 1 of 1	Attorney Docket Number	13621-43433	

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
WJV	A	WOLF, STANLEY PH.D. AND TAUBER, RICHARD N. PH.D., "SILICON PROCESSING FOR THE VLSI ERA, Volume 1: Process Technology," Book, 1st ed., Lattice Press (Sunset Beach, California), p. 430-437, (February 8, 1986).	
	B	ZIEGLER, J.F.; BIRSACK, J.P., LITTMARK, U., "THE STOPPING AND RANGE OF IONS IN SOLIDS," Book, Pergamon Press (U.S.A, U.K., Canada, Australia, Federal Republic of Germany), p. 109-110, 2, (February 8, 1985).	
	C	FERAIN, E.AND LEGRAS, R., "Track-etched membrane: dynamics of pore formation," Journal, Elsevier Science B.V. (North Holland), No. B84, p. 331-336, (February 8, 1994).	
	D	OKUYAMA, Y; HASHIMOTO, T.; KOGUCHI, T., "High Dose Ion Implantation into Photoresist," Journal, J. Electrochem. Soc. (Japan), Vol. 125 (No. 8), p. 1293-1298, (August 8, 1978).	
	E	VALIEV, K.A.; VELIKOV, L.V.; DUSHENKOV, S.D., "Pore formation in PMMA during x-ray exposure," Journal, Sov. Phys. Tech. Phys. (USSR), Vol. 32 (No. 7), p. 862-863, (February 8, 1988).	
	F	ORVEK, KEVI J.; HUFFMAN, CRAIG, "CARBONIZED LAYER FORMATION IN ION IMPLANTED PHOTORESIST MASKS," Journal, Elsevier Science Publishers BV (North Holland, Amsterdam), Vol. B (No. 7/8), p. 501-506, (February 8, 1985).	
	G	HICKS, C. et al., "Development and Clinical Assessment of an Artificial Cornea," Journal, Progress in Retinal and Eye Research, Elsevier Science Ltd. (Great Britain), Vol. 19 (No. 2), p 149-170 (2000).	
	H	TRAUTMAN, C., et al., "Etching threshold for ion tracks in polyimide," Journal, Nuclear Instruments and Methods in Physics Research B, Elsevier Science B.V. (North Holland, Amsterdam), Vol. B (No. 115), p. 429-433 (1996)	
	I	VIRK, H.S., et al., "Effects on insulators of swift-heavy-ion irradiation: ion-track technology," Journal, J. Phys. D: Appl. Phys., IOP Publishing Ltd. (UK), Vol. 31, p. 3139-3145, (1998).	
MDV	J	YASHAR, Alyson G., "Artificial iris device may reduce glare," Magazine, Opthamology Times, Advanstar Communications, Inc., (September 15, 2000)	

Examiner Signature	<i>M. Vargot</i>	Date Considered	11/30/05
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